

AMENDMENT TO THE CLAIMS

1 (Cancelled)

2.(Currently Amended) The vaporization system of claim 2228 wherein the at least one source comprises ~~a sources of a plurality of different gases connected to respective ones of the plurality of gas inlets the the atomizer, and includes whereby a plurality of different types of gases are selectively provided to form the gas stream selectively introduceable into the inlet.~~

3.(Currently Amended) The vaporization system of claim 2228 wherein the at least one source ~~comprises sources of is the source of liquid, and a plurality of different liquidsgases selectively introduceable intoto form the atomizergas stream.~~

4.(Currently Amended) The vaporization system of claim 2228 wherein the ~~gas and liquid inlets each comprise atomizer has a plurality of passageways, defined therein, the at least one the sources of gas and liquid each -source comprising sources of the first source andcomprises a plurality of different gases and different liquids, respectively-sources, and each different gas source being connected to a separate passageway, and wherein the second source is a source ofeach different liquid source and comprises a plurality of different types of liquid, each source of the different types of liquid being connected to a selected separateone of the passageways of the atomizer.~~

5.(Currently Amended) The vaporization system of claim 2228 wherein each of the ~~firstgas and liquidsecond~~ sources has a flow controller between the source and the ~~vaporization chamberatomizer~~.

6.(Currently Amended) The vaporization system of claim 22~~28~~, wherein both of the gas first and liquid~~second~~ sources comprise a plurality of gas or liquid materials from the respective source.

7.(Cancelled)

8.(Cancelled)

9.(Cancelled)

10.(Cancelled)

11.(Cancelled)

12.(Currently Amended) The vaporization system of claim 22, wherein a process chamber for vapor deposition and film formation is combined with the vaporization chamber, the outlet of the housing being connected to an inlet of the process chamber.

13.(Cancelled)

14.(Cancelled)

15.(Cancelled)

16.(Cancelled)

17.(Cancelled)

18.(Cancelled)

19.(Cancelled)

20.(Cancelled)

21.(Cancelled)

22.(Currently Amended) A vaporization system for vaporizing material carried in a gas stream, including a vaporization chamber receiving an aerosol from an atomizer, the aerosol comprising gas and liquid droplets from first and second respective gas and liquid sources, at least one of the sources comprising a plurality of different individually selectable materials, said vaporization chamber including a housing having walls defining the vaporization chamber, the housing having an inlet in a first wall and an outlet in a second wall, a heated surface member comprising a first metal block in the housing spaced from the first wall and having a plurality of individual passageways therethrough providing heated surfaces, a separate bore through the first metal block, the separate bore being substantially parallel to and of larger cross section than each individual passageway, and the separate bore being aligned with the inlet through which the aerosol is discharged into the vaporization chamber, and an orifice in the first metal block directly aligned with the inlet, said orifice forming an opening leading to the separate bore in the first metal block and being positioned to create a negative pressure in a space between the first wall and the first metal block such that aerosol discharged from the bore at an end remote from the space is drawn into the space through the plurality of individual passageways and recirculated through the separate bore, the aerosol droplets being vaporized by heat from the heated surfaces of the individual passageways in the first metal block.

23.(Previously Presented) The vaporization system of claim 22, wherein the orifice is no greater in size than substantially the same size as the bore.

24.(Previously Presented) The vaporization system of claim 23 wherein the aerosol forms a gas jet through the inlet.

25.(Cancelled)

26. (Previously Presented) The vaporization system of claim 22 wherein there is a second metal block in the interior vaporization chamber having a plurality of passageways therethrough, the second metal block being spaced from the first metal block and positioned between the first metal block and the outlet of the housing.

27.(Previously Presented) The vaporization system of claim 26 wherein the second metal block has an imperforate surface aligned with the bore in the first metal block to divert gas striking the imperforate surface laterally outwardly toward the passageways in the second metal block.

28. (New) A vaporization system for vaporizing material carried in a gas stream, said system including an outer housing defining a vaporization chamber, a heated surface member in the vaporization chamber, an atomizer comprising a passageway open to the vaporization chamber and having a plurality of separate liquid inlets and a gas inlet, a plurality of liquid sources of different liquid precursors, each source of a different liquid precursor being connected to a separate one of the liquid inlets, the plurality of liquid sources being separately controllable to provide a flow of a liquid precursor to each of the plurality of liquid inlets, at least one source of gas connected to the gas inlet, said gas inlet providing a gas stream through the passageway to form liquid droplets of liquid flowing through at least one of the plurality of liquid inlets for introduction into the vaporization chamber, material in the gas stream being vaporized in the vaporization chamber by heat from the heated surface member.